

Inventor: Garo J. Derderian
Title: Deposition Methods
Assignee: Micron Technology, Inc.
Docket No. MI22-2373

INFORMATION DISCLOSURE STATEMENT

PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98


In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application. The above-identified application is a continuation application of co-pending application Serial No. 10/261,735, filed September 30, 2002. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned. 37 C.F.R. § 1.98(d) and MPEP § 609(2).

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: 30 Sep 2003

By: 
James E. Lake
Reg. No. 44,854

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2373	PRIORITY SERIAL NO. 10/261,735			
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Garro J. Derderian				
				PRIORITY FILING DATE September 30, 2002		PRIORITY GROUP 1762		
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	5,270,247	12/1993	Sakuma et al				
	AB	6,270,572	08/2001	Kim et al				
	AC	6,083,832	07/2000	Sugai				
	AD	4,369,105	01/1983	Caldwell et al				
	AE	4,831,003	05/1989	Lang et al				
	AF	6,287,965	09/2001	Kang et al				
	AG	5,480,818	01/1996	Matsumoto et al				
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	AJ	5,916,365	06/1999	Sherman				
	AK	6,335,561	03/2000	Sandhu				
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		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM	EP 0794568	10/1997	Europe				
	AN	05-251339	09/1993	Japan				
	AO							
	AP							
	AQ							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
		AR	Kiyoko et al., Patent Abstract Application No. 04-024917 (JP 9224917, 09/1993), "Semiconductor Substrate and Its Manufacture."					
		AS	Ritala, et al., "Atomic Layer Epitaxy - A Valuable Tool for Nanotechnology?" Nanotechnology, Vol. 10, No. 1, pps. 19-24, March 1999.					
		AT	George, et al., "Surface Chemistry for Atomic Layer Growth", Journal of Physical Chemistry, Vol. 100, No. 31, pps. 13121-13131, August 1, 1996.					
		AU	Suntola, "Atomic Layer Epitaxy", Handbook of Crystal Growth, Vol. 3, Chapter 14, pps. 602-663.					
		AV	Vernon, S.M., "Low-cost, high-efficiency solar cells utilizing GaAs-on-Si technology." Dialog Abstract of Report No. NREL/TP-451-5353; 04/1993.					
EXAMINER		DATE CONSIDERED						
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

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U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	4,913,090	04/1990	Harada et al			
	AB	6,307,184	10/2001	Womack et al			
	AC	5,616,208	04/1997	Lee			
	AD	6,203,619	03/2001	McMillan			
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	AJ	6,355,561	03/2002	Sandhu et al			
	AK	6,335,561	01/2002	Imoto			
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FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
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	AN						
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR		Suntola, "Surface Chemistry of Materials Deposition at Atomic Layer Level", Applied Surface Science, vol. 100/101, March 1996, pp. 391-398.				
	AS		Aarik et al, "Effect of Growth Conditions on Formation of TiO ₂ -II Thin Films in Atomic Layer Deposition Process", Journal of Crystal Growth, Vol. 181, August 1997, pp. 259-264.				
	AT		Skarp, "ALE-Reactor for Large Area Depositions", Applied Surface Science, vol. 112, March 1997, pp. 251-254.				
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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-2373	PRIORITY SERIAL NO. 10/261,735		
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				PRIORITY FILING DATE September 30, 2002		PRIORITY GROUP 1762	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	09/652,533		Sandhu			08/2000
	AB	09/643,004		Mercaldi			08/2000
	AC	09/927,230		Doan			08/2001
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*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	6,479,902	11/2002	Lopatin et al			
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	AC	6,368,954	04/2002	Lopatin et al			
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	AH	2002/0125516	09/2002	Marsh et al			
	AI						
	AJ						
	AK						
	AL						
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	AN						
	AO						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AP		Aarik, et al, "Control of Thin Film Structure by Reactant Pressure in Atomic Layer Deposition of TiO ₂ ," Journal of Crystal Growth, 169 (1996) pgs. 496-502				
	AQ						
	AR						
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